

Special Issue

Advanced Machining Technology on the Hard-to-Processing Materials for the Power Semiconductors

Review

- Overview and Technical Issue on the Hard-to-Processing Technique for the Power Semiconductors
Keisuke SUZUKI431

Lecture

- Next Generation CMP Process Technique for Hard-to-Process Single Crystals
Hideo AIDA, Hidetoshi TAKEDA, Tadakazu MIYASHITA,
Atsushi KAJIKURA and Toshiro DOI435
- Slurryless Plasma-Assisted Polishing and Electrochemical Mechanical Polishing of Difficult to Polish Materials
Kazuya YAMAMURA440
- Recent Progress of Diamond Semiconductor Devices—2-Inch Wafer Growth and Power Device Fabrication—
Makoto KASU and Seong-Woo KIM445
- Ultra-Fine Polishing Technique for Diamond Substrates and Its Application to Semiconductor Devices with Improved Heat Dissipation Performance
Shuichi HIZA and Akihisa KUBOTA449
- Attempts on Surface Generation with Biocompatibility via Combination of ELID-Grinding and CMP
Hitoshi OHMORI, Syuhei KUROKAWA and Taku SUGAWARA453

- My Experience in Precision Engineering
Hiroshi MIZUMOTO465

- Gravure & Interview
Research Center for Three-Dimensional Semiconductors427
Tadashi SUETSUGU
Interview : Keisuke SUZUKI

- Student Forum
The Art of Ticking Time—Moving Forward with Persistence—459

- Introduction of Laboratories
Department of Intelligent Mechanical Engineering, Faculty of Engineering, Fukuoka Institute of Technology463

- Visit to Corporate Members
SHIMADZU CORPORATION469

- Information 471, 510
- JSPE Affiliate News 466
- Corporate Members 512
- From the Lecture Committee 告 6-1
- Editor's Note 告 6-10

Paper

- A Proposal of Template Matching Based on Pixel Selection for Constraint Rotated Patterns ————— 514
Naoya NAKABAYASHI, Sakura EBA, Hiroki KOBAYASHI and Manabu HASHIMOTO
- Influence of NaCl-Electrolytic Oxidizing Water on Polished Surface of Permalloy Material 45 ————— 521
Unkai SATO and Hideki KAWAKUBO

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